

C2 4. (Amended) An inspection method using an electron beam according to claim 1, further comprising the steps of:
scanning said specimen by using said electron beam; and
detecting charged particles emanating from said specimen and converting said detected charged particles into an electrical signal.

C3 9. (Amended) An inspection apparatus for detecting a defect of a specimen by using an electron beam, said apparatus comprising:
an electron source for drawing the electron beam set to at least 100nA of beam current;
a convergence lens for converging said electron beam so as to form a crossover between said convergence lens and said specimen;
a deflector for deflecting said electron beam by taking a crossover as fulcrum; and
a power supply applying a retarding voltage for decelerating the electron beam to the specimen, wherein said power supply applies a magnitude of said retarding voltage to said specimen based on the nature of said specimen.

C4 16. (Amended) An inspection apparatus using an electron beam according to claim 9, wherein an electron set at a positive electric potential with respect to said deceleration voltage is provided between said specimen and said charged particle detector.

REMARKS

Claims 1, 4-13 and 16 are pending. By this Amendment, claims 2, 3, 14 and 15 are canceled and claims 1, 4, 9, and 16 are amended.

The subject matter of claims 2 and 3 has been incorporated into claim 1. The subject matter of claims 14 and 15 has been incorporated into claim 9.

The Office Action rejects claims 1-4, 9, 10, 14 and 15 under 35 U.S.C. § 102 over Feuerbaum, rejects claims 5, 6, 11 and 16 under 35 U.S.C. § 103 over Feuerbaum in view of Meisburger, rejects claims 7 and 12 under 35 U.S.C. § 103 over Feuerbaum in view of Rose